



2823
Docket: 740756-1894

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of)
Shunpei YAMAZAKI et al.) Group Art Unit: 2823
Serial No. 09/197,534) Examiner: W. David Coleman
Filed: November 23, 1998) Allowed: September 10, 2003
For: Laser Process) Date: October 21, 2003

**REQUEST FOR ACKNOWLEDGMENT OF
INFORMATION DISCLOSURE STATEMENT**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

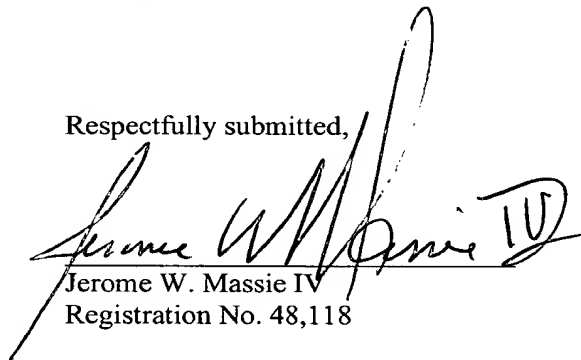
Sir:

Information Disclosure Statements with Forms PTO-1449 were filed in the above-identified patent application on June 15, 2000, December 19, 2000 and August 20, 2003. Applicants have not yet received back from the Examiner a copy of the Forms PTO-1449 initialed to acknowledge the fact that the Examiner has considered the cited disclosed information.

The Examiner is requested to initial and return to the undersigned a copy of the subject Forms PTO-1449.

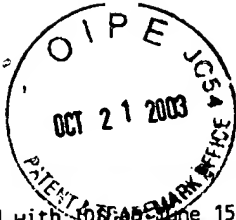
Should there be any questions concerning this communication, please telephone the undersigned at the number set forth below.

Respectfully submitted,



Jerome W. Massie IV
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Submitted with USPTO Form 15, 2000

Sheet 1 of 4

Form PTO-1449
(Rev. 8-83)U.S. Department of Commerce
Patent and Trademark OfficeAtty.Docket No.
0756-1894Serial No.
09/197,534**INFORMATION DISCLOSURE STATEMENT**

(Use several sheets if necessary)

Applicant
Shunpei Yamazaki et al.Filing Date
November 23, 1998Group
2874**U.S. PATENT DOCUMENTS**

| Examiner Initial | Document Number | Date | Name | Class | Subclass | Filing Date (if appropriate) |
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OCT 21 2003

Submitted with IDS on June 15, 2000

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PATENT & TRADEMARK OFFICE
Form PTO-1449
(Rev. 8-83)U.S. Department of Commerce
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| Form PTO-1449 (Rev. 8-78) | | U.S. Department of Commerce Patent and Trademark Office | | Atty.Docket No. 0756-1894 | | Serial No. 09/197,534 | |
| INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary) | | | | Applicant Shunpei Yamazaki et al. | | | |
| | | | | Filing Date November 23, 1998 | | Group 2874 | |

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PATENT & TRADEMARK
OFFICE 1449
(Rev. 8-83)U.S. Department of Commerce
Patent and Trademark OfficeAtty.Docket No.
0756-1894Serial No.
09/197,534**INFORMATION DISCLOSURE STATEMENT**

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2874**U.S. PATENT DOCUMENTS**

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Form PTO-1449 U.S. Department of Commerce
(Rev. 8-83) Patent and Trademark Office

Atty. Docket No.: 0756-1894

Serial No. 09/197,534

Applicant: SHUNPEI YAMAZAKI et al.

INFORMATION DISCLOSURE STATEMENT

(Use several sheets if necessary)

Filing Date: November 23, 1998

Group: 2874

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| Examiner Initial | Patent Number | Issue Date | Patentee | Class | Subclass | Filing Date (if approp.) |
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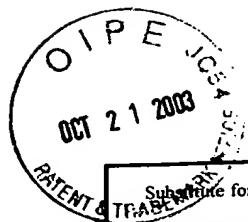
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| Substitute for form 1449A/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary) | | | | Complete if Known | |
| | | | | Application Number | 09/197,534 |
| | | | | Filing Date | November 23, 1998 |
| | | | | First Named Inventor | Shunpei YAMAZAKI et al. |
| | | | | Art Unit | 2823 |
| | | | | Examiner Name | William D. Coleman |
| Sheet | 1 | of | 1 | Attorney Docket Number | 740756-1894 |

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|--------------------------------|-----------------------|--|--------------------------------|---|---|
| Examiner Initials ² | Cite No. ¹ | U.S. Patent Document | Publication Date MM-DD-YYYY | Name of Patentee or Applicant of Cited Document | Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear |
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| OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS | | | |
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| Examiner Initials ² | Cite No. ¹ | Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published. | T ² |
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